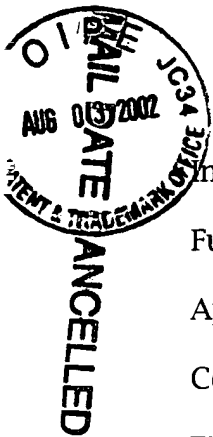


RCE / 1765  
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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



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In re application of

Fumiyoshi ONO

Appln. No.: 09/672,776

Confirmation No.: 2256

Filed: September 29, 2000

Docket No: Q61045

Group Art Unit: 1765

Examiner: Charlotte A. Brown

For: COMPOSITION FOR POLISHING METAL ON SEMICONDUCTOR WAFER AND  
METHOD OF USING SAME

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of  
time of two months, extending the time for responding to the Office Action of April 3,  
2002, and the Advisory Action of August 12, 2002, from July 3, 2002 to September 3,  
2002.

A check for the statutory fee of \$400.00 is attached. The USPTO is directed and  
authorized to charge all required fees, except for the Issue Fee and the Publication Fee,  
to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit  
Account. A duplicate copy of this sheet is enclosed.

09/04/2002 SSESKE1 00000044 09672776

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Date: September 3, 2002

Respectfully submitted,

*Keiko K. Takagi / Burel. Crane*  
Keiko K. Takagi  
Registration No. 47,121

BEST AVAILABLE COPY